

EXHIBIT K

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Ralph R. Veseli, Patent Attorney
Maria Paula Kovacs, Paralegal
Intellectual Property
Mail Stop D-106
LSI Logic Corporation
1551 McCarthy Blvd.
Milpitas, CA 95035

VIA FEDERAL EXPRESS

Re: Patent Application in Final Form for Execution
Sheldon Aronowitz, Valeriy Sukharev,
John Haywood, James P. Kimball, Helmut Puchner,
Ravindra Manohar Kapre, and Nicholas Eib
PROCESS FOR ETCHING A CONTROLLABLE
THICKNESS OF OXIDE ON AN INTEGRATED
CIRCUIT STRUCTURE ON A SEMICONDUCTOR
SUBSTRATE USING NITROGEN PLASMA AND
AN RF BIAS APPLIED TO THE SUBSTRATE
LSI Docket No. 99-039

Dear Ralph:

Enclosed are the followings documents for the above captioned LSI Logic patent docket which are to be used for the execution of the formal papers by the inventors:

1. Patent application on A4 paper;
2. One (1) sheet of formal drawings;
3. Declaration, Power of Attorney, and Petition to be signed by the inventors (in duplicate); and
4. Assignment to be signed by the inventors and witnessed (in duplicate).

Please note that per LSI's written instructions dated March 11, 1994, two copies (originals) of each of above items 3 and 4 are enclosed for execution, in duplicate, by the inventors. Naturally, the date on the Assignments should be the same as the date written on the Declarations.

LSI AVAILABLE COPY

Ralph R. Veseli, Patent Attorney
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After the inventors have executed the Declarations and the Assignments, please return one executed original of each, together with the original application and the drawings, to my office so that they can be filed in the USPTO. I will then send you a copy of everything which is filed in the USPTO.

Regards,



John P. Taylor
Patent Attorney

ALL INFORMATION CONTAINED
HEREIN IS UNCLASSIFIED
DATE 10-22-2014 BY SP